	Type	L #	Hits	Search Text	DBs	Comments
1	BRS	L1	145409	438/$.ccls.	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	
2	BRS	L2	878	1 and (MEMS or microelectromechanical or (tunable near (FP or fabry-perot) near filter))	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	
3	BRS	L3	16	2 and pattern$3 near (HR or coating)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	
4	BRS	L4	15	3 and (mask or photoresist)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	
5	BRS	L6	45	(miller-michael-f or le-minh-van or cook-christopher-c or nagle-steven-f).in.	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	
6	BRS	L7	22	6 and (MEMS or microelectromechanical or (tunable near (FP or fabry-perot) near filter))	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	
7	BRS	L8	2	7 and pattern$3 near (HR or coating)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	
8	BRS	L9	1417	(MEMS or microelectromechanical or (tunable near (FP or fabry-perot) near filter)).ti.	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	
9	BRS	L10	346	9 and (mask or photoresist)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	
10	BRS	L11	0	10 and pattern$3 near (HR or coating)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	
11	BRS	L12	298	10 and pattern$3	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	
12	BRS	L13	9638	(MEMS or microelectromechanical or (tunable near (FP or fabry-perot) near filter))	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	
13	BRS	L14	0	13 and pattern$3 near (antireflecting near coating)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	
14	BRS	L15	298	12 and (mask or photoresist)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	
15	BRS	L16	298	15 and pattern$3	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	
16	BRS	L18	0	13 and pattern$3 near (reflective near coating)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	
17	BRS	L17	25	16 and (reflective near coating)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	